

BNL-101723-2014-TECH RHIC/AP/68;BNL-101723-2013-IR

## Reducing the RF Voltage Requirement by Blowing up the Initial Emittance

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September 1988

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## **U.S. Department of Energy**

USDOE Office of Science (SC)

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by

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Experience with protons

showed that in creasing the Initial

Ex from Ex = 10 to Ex = 20

reduced RF Voltage required

by about 607s.

H. Hahn suggestion to try

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in creasing & x for Au at 8=100
to reduce VRF required.

## Theoretical Basis (Valid at high 8)

- i) Phase spacedensity indicates that op growth rate due to introbeom sculturing, decreases like 1/Tx4 ~ 1/Ex
- 2) Partition Rule,  $\sigma_E \simeq \sqrt{2} \, \sigma_X$ in dicates that  $\sigma_P$  growth rate

  in creases like  $(\sigma_X/\sigma_E)^2$

Phase space density factor should (destate)
dominate and op growth should decrease.

when Exis in creased.



